Amdt. Dated 03/02/2005 Reply to Office Action of 02/04/2005

Appl. No. 10/734,928

IN THE CLAIMS

Please amend claims 43 and 47 as follows below.

Please cancel claim 48 without prejudice.

The following is a listing of claims that replaces all prior versions, and listings, of claims in the application:

Listing of Marked Up Claims:

- 1 1-.22. (Cancelled).
- 1 23. (Previously Presented) A bipolar transistor,
- 2 comprising:
- 3 a substrate to provide a collector region;
- 4 a base region having an intrinsic base region and an
- 5 extrinsic base region, each of the intrinsic base region and
- 6 the extrinsic base region having a mono-crystalline portion
- 7 over a mono-crystalline portion of the substrate; and
- 8 an emitter structure over the intrinsic base region;
- 9 wherein the extrinsic base region is raised relative to
- 10 the intrinsic base region;
- 11 wherein the extrinsic base region has a thickness x and
- 12 the intrinsic base region has a thickness y, and wherein x
- 13 is greater than y.
- l 24. (Previously Presented) The bipolar transistor of
- 2 claim 23, wherein
- 3 the emitter structure includes

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4 a polysilicon emitter having a first portion with 5 a width a, a second portion with a width b, and a third 6 portion with a width c; 7 wherein c is greater than b which is greater than 8 a; and 9 wherein the first portion defines an emitter base 10 junction, and wherein the third portion defines an 11 emitter contact region. 1 25. (Previously Presented) The bipolar transistor of 2 claim 24, wherein 3 the emitter structure further includes a nitride spacer 4 directly adjacent to the polysilicon emitter. 1 26. (Original) The bipolar transistor of claim 23, 2 wherein 3 the extrinsic base region comprises: 4 a first epitaxial layer; and 5 a second epitaxial layer on the first epitaxial 6 layer. 1 27. (Previously Presented) The bipolar transistor of 2 claim 26, wherein 3 the first epitaxial layer is a SiGe epitaxial layer and 4 the second epitaxial layer is a heavily p-type doped Si 5 or SiGe epitaxial layer. 1 28. (Previously Presented) The bipolar transistor of 2 claim 23, wherein

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3 the bipolar transistor is an npn transistor.

1 29. (Previously Presented) A bipolar transistor,

2 comprising:

a substrate having a collector region, the collector

4 region being a collector terminal;

5 a first epitaxial silicon layer having a mono-

6 crystalline portion on a mono-crystalline portion of the

7 substrate;

8 an emitter stack on the first epitaxial silicon layer,

9 the emitter stack being an emitter terminal;

a second epitaxial silicon layer having a mono-

11 crystalline portion on the mono-crystalline portion of the

12 first epitaxial silicon layer located outside the emitter

13 stack;

14 wherein a region of the first epitaxial silicon layer

15 located under the emitter stack is an intrinsic base region

16 and a region of the second epitaxial silicon layer on

17 portions of the first epitaxial silicon layer located

18 outside the emitter stack being a raised extrinsic base

19 region;

wherein the raised extrinsic base region has a

21 thickness greater than a thickness of the intrinsic base

22 region; and

wherein the intrinsic base region and the raised

24 extrinsic base region provide a base terminal of the bipolar

25 transistor with lower resistivity.

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- 1 30. (Previously Presented) The bipolar transistor of
- 2 claim 29, wherein
- 3 the first epitaxial layer is a p-type Si, SiGe or
- 4 SiGe:C epitaxial layer and
- 5 the second epitaxial layer is a selectively deposited
- 6 heavily p-type doped Si epitaxial layer or a selectively
- 7 deposited heavily p-type doped SiGe epitaxial layer.
- 1 31. (Previously Presented) The bipolar transistor of
- 2 claim 29, wherein
- 3 the emitter stack includes
- 4 a nitride layer having an emitter window, and
- 5 a polysilicon emitter within the emitter window.
- 1 32. (Previously Presented) The bipolar transistor of
- 2 claim 29, wherein
- 3 the bipolar transistor is a Si, SiGe or SiGe:C npn
- 4 bipolar transistor.
- 1 33. (Previously Presented) A bipolar transistor
- 2 having a base, a collector, and an emitter, the bipolar
- 3 transistor comprising:
- 4 a substrate with a collector region;
- 5 a base region coupled to the substrate, the base region
- 6 having an intrinsic base region and an extrinsic base
- 7 region, each of the intrinsic base region and the extrinsic
- base region having a mono-crystalline portion over a mono-
- crystalline portion of the substrate;

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- 10 a polysilicon emitter structure coupled to the
- 11 intrinsic base region; and
- 12 wherein the extrinsic base region has a thickness X and

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- 13 the intrinsic base region has a thickness y, and wherein X
- 14 is greater than Y.
- 1 34. (Previously Presented) The bipolar transistor of
- 2 claim 33, wherein
- 3 the extrinsic base region is raised relative to the
- 4 intrinsic base region.
- 1 35. (Previously Presented) The bipolar transistor of
- 2 claim 33, wherein
- 3 the polysilicon emitter structure has a first portion
- 4 providing an emitter base junction, a second portion
- 5 providing conduction, and a third portion providing an
- 6 emitter contact region.
- 1 36. (Previously Presented) The bipolar transistor of
- 2 claim 35, wherein
- 3 the first portion of the polysilicon emitter structure
- 4 has a width A,
- 5 the second portion of the polysilicon emitter structure
- 6 has a width B differing from A,
- 7 the third portion of the polysilicon emitter structure
- 8 has a width C differing from A and C.
- 1 37. (Previously Presented) The bipolar transistor of
- 2 claim 36, wherein

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- 3 the width C is greater than the width B which is
- 4 greater than the width A.
- 1 38. (Previously Presented) The bipolar transistor of
- 2 claim 23, wherein
- 3 the extrinsic base region further has a poly-
- 4 crystalline portion over an oxide layer of the substrate.
- 1 39. (Previously Presented) The bipolar transistor of
- 2 claim 23, further comprising:
- 3 a silicide layer on a top surface of the extrinsic base
- 4 region to lower a contact resistance.
- 1 40. (Previously Presented) The bipolar transistor of
- 2 claim 39, wherein
- 3 the silicide layer is a refractory metal silicide layer
- 4 of CoSi₂ or TiSi₂.
- 1 41. (Previously Presented) The bipolar transistor of
- 2 claim 29, wherein
- 3 the first epitaxial layer further has a poly-
- 4 crystalline portion on an oxide layer of the substrate, and
- 5 the second epitaxial layer further has a has a poly-
- 6 crystalline portion on the poly-crystalline portion of the
- 7 first epitaxial layer.
- 1 42. (Previously Presented) The bipolar transistor of
- 2 claim 29, further comprising:

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- 3 a silicide layer on a top surface of the second
- 4 epitaxial silicon layer to lower a contact resistance.
- 1 43. (Currently Amended) The bipolar transistor of
- 2 claim [[40]] 42, wherein
- 3 the silicide layer is a refractory metal silicide layer
- 4 of CoSi₂ or TiSi₂.
- 1 44. (Previously Presented) The bipolar transistor of
- 2 claim 33, wherein
- 3 the extrinsic base region further has a poly-
- 4 crystalline portion over an oxide layer of the substrate.
- 1 45. (Previously Presented) The bipolar transistor of
- 2 claim 33, further comprising:
- 3 a silicide layer on a top surface of the extrinsic base
- 4 region to lower a contact resistance.
- 1 46. (Previously Presented) The bipolar transistor of
- 2 claim 45, wherein
- 3 the silicide layer is a refractory metal silicide layer
- 4 of CoSi₂ or TiSi₂.
- 1 47. (Currently Amended) A bipolar transistor,
- 2 comprising:
- 3 a substrate having a mono-crystalline portion and an
- 4 oxide portion, the substrate to provide a collector region;
- 5 a plurality of epitaxial layers over the substrate,
- 6 each of the plurality of epitaxial layers having a mono-

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7 crystalline portion over the mono-crystalline portion of the

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- 8 substrate and a poly-crystalline portion over the oxide
- 9 portion of the substrate; and
- 10 a polysilicon emitter on the mono-crystalline portion
- 11 of a first epitaxial layer of the plurality of epitaxial
- 12 layers;
- 13 wherein the plurality of epitaxial layers to provide a
- 14 raised extrinsic base located outside the polysilicon
- 15 emitter, the mono-crystalline portion of the first epitaxial
- 16 layer under the polysilicon emitter to provide an intrinsic
- 17 base, and the raised extrinsic base is thicker than the
- 18 intrinsic base.
- 1 48. (Cancelled)
- 49. (Previously Presented) The bipolar transistor of 1
- 2 claim 47, wherein
- 3 at least a second epitaxial layer of the plurality of
- 4 epitaxial layers is coupled to the first epitaxial layer to
- 5 provide the raised extrinsic base.
- 1 50. (Previously Presented) The bipolar transistor of
- 2 claim 49, wherein
- 3 the first epitaxial layer is a SiGe epitaxial layer and
- 4 the at least second epitaxial layer is a heavily p-type
- 5 doped Si or SiGe epitaxial layer.
- 1 51. (Previously Presented) The bipolar transistor of
- 2 claim 47, further comprising:

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- 3 a silicide layer on a top surface of the raised
- 4 extrinsic base to lower a contact resistance.
- 1 52. (Previously Presented) The bipolar transistor of

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- 2 claim 51, wherein
- 3 the silicide layer is a refractory metal silicide layer
- 4 of CoSi₂ or TiSi₂.
- 1 53. (Previously Presented) The bipolar transistor of
- 2 claim 47, wherein
- 3 the bipolar transistor is an npn transistor.
- 1 54. (Previously Presented) The bipolar transistor of
- 2 claim 53, wherein
- 3 the npn transistor is a Si, SiGe or SiGe:C npn bipolar
- 4 transistor.